

This Page Is Inserted by IFW Operations
and is not a part of the Official Record

BEST AVAILABLE IMAGES

Defective images within this document are accurate representations of the original documents submitted by the applicant.

Defects in the images may include (but are not limited to):

- BLACK BORDERS
- TEXT CUT OFF AT TOP, BOTTOM OR SIDES
- FADED TEXT
- ILLEGIBLE TEXT
- SKEWED/SLANTED IMAGES
- COLORED PHOTOS
- BLACK OR VERY BLACK AND WHITE DARK PHOTOS
- GRAY SCALE DOCUMENTS

IMAGES ARE BEST AVAILABLE COPY.

**As rescanning documents *will not* correct images,
please do not report the images to the
Image Problem Mailbox.**



OSMM&N File No. 0039-7632-0X

Dept.: C:

By: NFO/SUK/ils

Serial No. 09/531,163

In the matter of the Application of: Hirovuki YANO, et al.

For: AQUEOUS DISPERSION, AQUEOUS DISPERION FOR CHEMICAL MECHANICAL POLISHING USED FOR MANUFACTURE OF SEMICONDUCTOR DEVICES, METHOD FOR MANUFACTURE OF SEMICONDUCTOR DEVICES, AND METHOD FOR FORMATION OF EMBEDDED WIRING

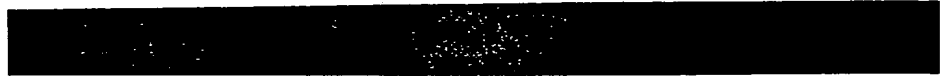
Due Date: February 19, 2004

The following has been received in the U.S. Patent Office on the date stamped hereon:

- Dep. Acct. Order Form
- PTO Cover Letter
- Request for Refund
- Copy of Pair Report (3 pages)



[Handwritten signature]

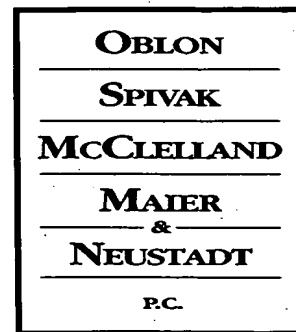


[Handwritten word "Copy"]



Docket No.: 0039-7632-0X

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313



RE: Application Serial No.: 09/531,163

Applicants: Hiroyuki YANO, et al.

Filing Date: March 17, 2000

For: AQUEOUS DISPERSION, AQUEOUS DISPERSION
FOR CHEMICAL MECHANICAL POLISHING USED
FOR MANUFACTURE OF SEMICONDUCTOR
DEVICES, METHOD FOR MANUFACTURE OF
SEMICONDUCTOR DEVICES, AND METHOD FOR
FORMATION OF EMBEDDED WIRING

Group Art Unit: 1765

Examiner: DEO, DUY VU NGUYEN

SIR:

Attached hereto for filing are the following papers:

Request for Refund

Copy of PAIR Report (3 pages)

Our check in the amount of \$0.00 is attached covering any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R. 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. 15-0030. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.

Norman F. Oblon

Registration No. 24,618

Stefan U. Koschmieder, Ph.D.

Registration No. 50,238

Customer Number

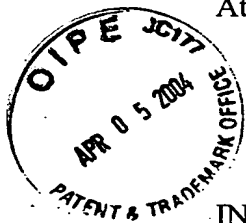
22850

(703) 413-3000 (phone)

(703) 413-2220 (fax)

COPY

Atty. Docket No. 0039-7632-0X



IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF:

Hiroyuki YANO, et al.
NGUYEN

:EXAMINER: DEO, DUY VU

SERIAL NO.: 09/531,163

:GROUP ART UNIT: 1765

FOR: AQUEOUS DISPERSION, AQUEOUS DISPERSION FOR CHEMICAL
MECHANICAL POLISHING USED FOR MANUFACTURE OF
SEMICONDUCTOR DEVICES, METHOD FOR MANUFACTURE OF
SEMICONDUCTOR DEVICES, AND METHOD FOR FORMATION OF
EMBEDDED WIRING

REQUEST FOR REFUND

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

Pursuant to 37 CFR 1.26, Applicants request a refund of the Notice of Appeal
and one month extension of time that were inadvertently paid on February 2, 2004.

REMARKS

Applicants request a refund of \$440.00 paid on February 2, 2004, for a Notice
of Appeal and one month extension of time. A Notice of Allowability was indicated
on January 21, 2004 as evidenced by the attached sheets, therefore the filing of the
Notice of Appeal and one month extension of time were not required, and this request
is believed to be justified.

COPY

Application No. 09/531,003

Please credit the refund to our Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.

Norman F. Oblon
Registration No. 24,618

Stefan U. Koschmieder, Ph.D.
Registration No. 50,238

Customer Number

22850

Tel: (703) 413-3000

Fax: (703) 413-2220

NFO:SUK:ils

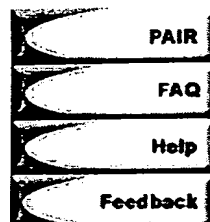
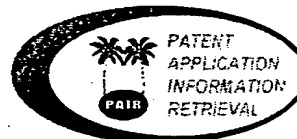
COPY



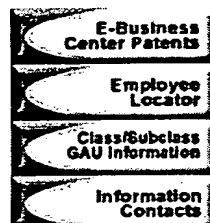
United States Patent and Trademark Office

[Home](#) | [Site Index](#) | [Search](#) | [Guides](#) | [Contacts](#) | [eBusiness](#) | [eBiz alerts](#) | [News](#) | [Help](#)

PATENT APPLICATION INFORMATION RETRIEVAL



Other Links



Search results for application number:09/531,163			
Application Number:	09/531,163	Customer Number:	22850
Filing or 371 (c) Date:	03-17-2000	Status:	Allowed -- Notice of Allow Mailed -- Issue Revision Completed
Application Type:	Utility	Status Date:	02-04-2004
Examiner Name:	DEO, DUY VU NGUYEN	Location:	ELECTRONIC
Group Art Unit:	1765	Location Date:	01-06-2004
Confirmation Number:	5064	Earliest Publication No:	-
Attorney Docket Number:	0039-7632-0X	Earliest Publication Date:	-
Class/ Sub-Class:	438/692	Patent Number:	-
First Named Inventor:	Hiroyuki Yano, Yokohama-shi, (JP)	Issue Date of Patent:	-
Title Of Invention:	AQUEOUS DISPERSION, AQUEOUS DISPERSION FOR CHEMICAL MECHANICAL POLISHING USED FOR MANUFACTURE OF SEMICONDUCTOR DEVICES, METHOD FOR MANUFACTURE OF SEMICONDUCTOR DEVICES, AND METHOD FOR FORMATION OF EMBEDDED WIRING		

Select Search Option

Image File Wrapper

Search

Foreign Priority

Patent Term Extension History

Publication Review

File History		
Number	Date	Contents Description
72	02-04-2004	Mail Notice of Allowance
71	01-29-2004	Issue Revision Completed
70	01-30-2004	Notice of Allowance Data Verification Completed
69	01-21-2004	Notice of Allowability
68	01-14-2004	Date Forwarded to Examiner
67	12-23-2003	Amendment after Final Rejection
66	01-07-2004	Mail Examiner Interview Summary (PTOL - 413)
65	12-17-2003	Examiner Interview Summary Record (PTOL - 413)

64	12-17-2003	Examiner Interview Summary Record (PTOL - 413)
63	10-02-2003	Mail Final Rejection (PTOL - 326)
62	09-30-2003	Final Rejection
61	08-04-2003	Date Forwarded to Examiner
60	07-30-2003	Response after Non-Final Action
59	04-30-2003	Mail Non-Final Rejection
58	04-29-2003	Non-Final Rejection
57	04-04-2003	Information Disclosure Statement (IDS) Filed
56	03-14-2003	Affidavit(s) (Rule 131 or 132) or Exhibit(s) Received
55	03-20-2003	Date Forwarded to Examiner
53	03-20-2003	Date Forwarded to Examiner
52	03-14-2003	Request for Continued Examination (RCE)
51	03-20-2003	Express Abandonment (for Entry of CPA / RCE / Rule129)
50	03-14-2003	Workflow - Request for RCE - Begin
49	02-28-2003	Mail Advisory Action (PTOL - 303)
48	02-26-2003	Advisory Action (PTOL-303)
47	02-13-2003	Affidavit(s) (Rule 131 or 132) or Exhibit(s) Received
46	02-21-2003	Date Forwarded to Examiner
45	02-13-2003	Amendment after Final Rejection
44	11-15-2002	Mail Final Rejection (PTOL - 326)
43	11-15-2002	Final Rejection
42	09-24-2002	Date Forwarded to Examiner
41	09-23-2002	Response after Non-Final Action
40	06-21-2002	Mail Non-Final Rejection
39	06-20-2002	Non-Final Rejection
38	05-21-2002	Information Disclosure Statement (IDS) Filed
36	05-08-2002	Date Forwarded to Examiner
35	05-03-2002	Request for Continued Examination (RCE)
34	05-08-2002	Express Abandonment (for Entry of CPA / RCE / Rule129)
33	05-03-2002	Request for Extension of Time - Granted
32	05-03-2002	Workflow - Request for RCE - Begin
31	04-16-2002	Mail Advisory Action (PTOL - 303)
30	04-15-2002	Advisory Action (PTOL-303)
29	04-11-2002	Date Forwarded to Examiner
28	04-04-2002	Amendment after Final Rejection
27	04-04-2002	Request for Extension of Time - Granted
26	03-15-2002	Mail Advisory Action (PTOL - 303)
25	03-14-2002	Advisory Action (PTOL-303)
24	03-04-2002	Date Forwarded to Examiner
23	02-28-2002	Amendment after Final Rejection
22	12-04-2001	Mail Final Rejection (PTOL - 326)
21	12-03-2001	Final Rejection
20	10-05-2001	Information Disclosure Statement (IDS) Filed
19	10-10-2001	Date Forwarded to Examiner
18	10-05-2001	Response after Non-Final Action
17	03-20-2001	Case Docketed to Examiner in GAU
16	08-15-2001	Information Disclosure Statement (IDS) Filed
15	07-05-2001	Mail Non-Final Rejection
14	06-29-2001	Non-Final Rejection
13	06-19-2001	Case Docketed to Examiner in GAU
12	04-19-2001	Date Forwarded to Examiner
11	04-17-2001	Response to Election / Restriction Filed
10	03-20-2001	Mail Restriction Requirement

9	03-20-2001	Requirement for Restriction / Election
8	07-24-2000	Information Disclosure Statement (IDS) Filed
7	07-17-2000	Information Disclosure Statement (IDS) Filed
6	06-21-2000	Request for Foreign Priority (Priority Papers May Be Included)
5	06-07-2000	Case Docketed to Examiner in GAU
4	05-31-2000	Application Dispatched from OIPE
3	05-31-2000	Correspondence Address Change
2	04-12-2000	IFW Scan & PACR Auto Security Review
1	03-17-2000	Initial Exam Team nn

[|.HOME](#) | [INDEX](#) | [SEARCH](#) | [eBUSINESS](#) | [CONTACT US](#) | [PRIVACY STATEMENT](#)

COPY